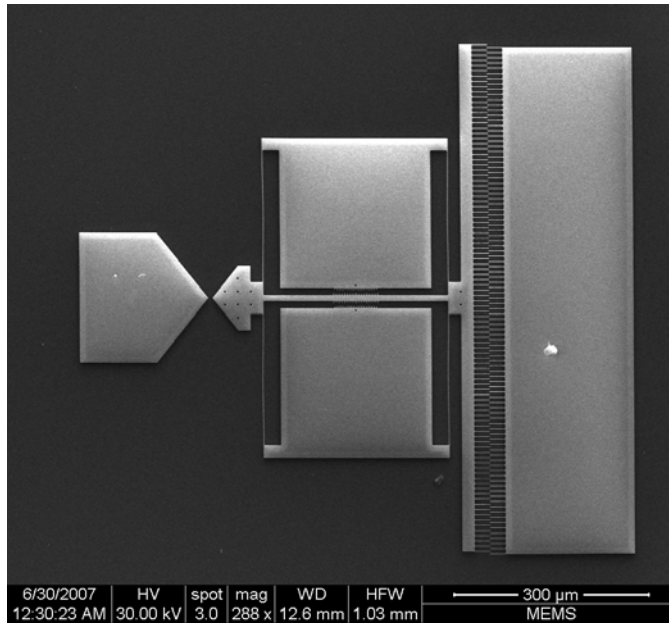


Micro-electro-mechanical devices for Nano-mechanical testing

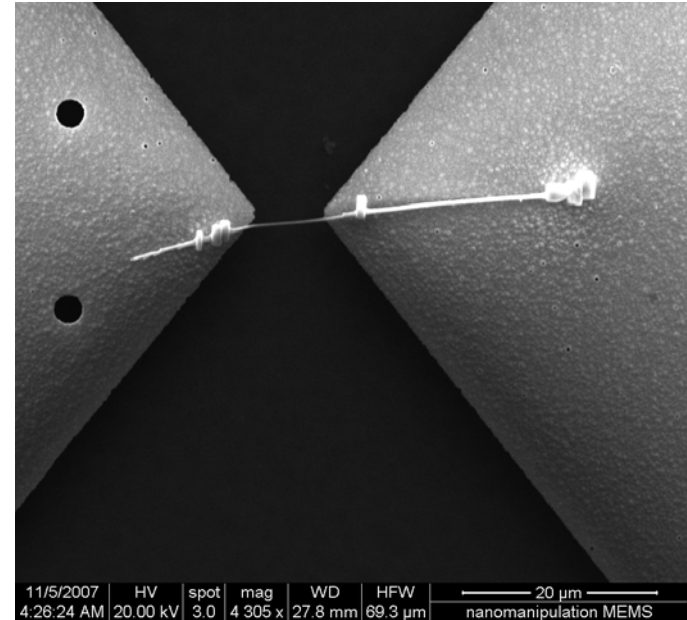
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DESCRIPTION OF WORK

- ◆ The goal of this research is to develop a MEMS platform that allows *in situ* quantitative mechanical characterization of 1-D nanostructures, such as metallic nanowires and carbon nanotubes, within an SEM chamber.



MEMS Platform for Tension Testing



Nickel nanowire clamped across MEMS stage
using ion induced Pt deposition